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Docket: 0756-1551

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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Continuation Application of: )  
Shunpei YAMAZAKI et al. )  
Based On Serial No. 08/160,909 ) Art Unit: 1107  
Which Was Filed: December 3, 1993 ) Examiner: Wilczewski  
For: METHOD OF FABRICATING )  
SEMICONDUCTOR DEVICES )  
AND APPARATUS FOR PROCESSING )  
A SEMICONDUCTOR ) Date: August 2, 1996

PRELIMINARY AMENDMENT

Honorable Assistant Commissioner for Patents  
Washington, D.C. 20231

Sir:

Please preliminarily amend the subject application as follows:

IN THE CLAIMS:

Please amend claim 15 as follows:

15. (Amended) The apparatus of claim 8 [14] wherein said vacuum apparatus, said irradiation apparatus and said preliminary chamber can be

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